			•	10/674,961	Reexa		cant(s)Patent Under amination .EGARI ET AL.	
		Notice of Reference	s Cited	Examiner	Examiner Alexander G. Ghyka			
				Alexander G			Page 1 of 1	
				U.S. PATENT DOCUM	ENTS	•	<u> </u>	
*		Document Number Country Code-Number-Kind Code	Date MM-YYYY		Name		Classification	
	A	US-						
	В	US						
	С	US-						
	D	US-				_		
	Ε	US-						
	F	US						
	G	US-						
	Н	US-						
	ı	US-						
	J	US-						
	к	US-						
	L	US-		X		_		
	М	US-						
				OREIGN PATENT DOC	UMENTE			
*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Country		Classification	
	N							
	0							
	Р							
	Q							
	R							
	s				<u>.</u>			
<u>./</u>	4							
		.		NON-PATENT DOCUM	IENTS)	
*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)						
	U	Yom et al, Growth of gamma alumina thin films on silicon by MOCVD,Thin Solid Films 1992, pgs 72-75.						
	٧							
	w							
	×							

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

U.S. Patent and Trademark Office PTO-892 (Rev. 01-2001)

Notice of References Cited 6/26/0 \$

Part of Paper No. 06262005